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Application ID: 10663603



Title of Invention: METHODS AND SYSTEMS FOR
INSPECTION OF AN ENTIRE
WAFER SURFACE USING MULTIPLE
DETECTION CHANNELS

First Named Inventor: Lionel Kuhlmann

Domestic/Foreign Application: Domestic Application

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Statement

Filing Type:

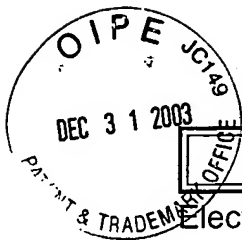
Confirmation number: 3534

Attorney Docket Number: 5589-06100

Total Fees Authorized:


Digital Certificate Holder: cn=Kevin L. Daffer,ou=Registered Attorneys,ou=Patent and Trademark
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TRANSMITTAL

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Stylesheet Version v1.1.0

| Title of Invention | METHODS AND SYSTEMS FOR INSPECTION OF AN ENTIRE WAFER SURFACE USING MULTIPLE DETECTION CHANNELS | | | | | | | | | |
|--|--|----------------|---------------------------|-------------|----------------|---|-----------------|------------|--|------------|
| <p>Application Number: 10/663603 </p> <p>Date: 2003-09-16</p> <p>First Named Applicant: Lionel Kuhlmann</p> <p>Confirmation Number: 3534</p> <p>Attorney Docket Number: 5589-06100</p> | | | | | | | | | | |
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| <table border="1"><thead><tr><th>Submitted by:</th><th>Elec. Sign.</th><th>Sign. Capacity</th></tr></thead><tbody><tr><td>Kevin L. Daffer Registered Number: 34146</td><td>Kevin L. Daffer</td><td>Attorney</td></tr></tbody></table> | | | Submitted by: | Elec. Sign. | Sign. Capacity | Kevin L. Daffer Registered Number: 34146 | Kevin L. Daffer | Attorney | | |
| Submitted by: | Elec. Sign. | Sign. Capacity | | | | | | | | |
| Kevin L. Daffer Registered Number: 34146 | Kevin L. Daffer | Attorney | | | | | | | | |
| <table><tr><td>Documents being submitted</td><td>Files</td></tr><tr><td>us-ids</td><td>558906100IDS-usidst.xml</td></tr><tr><td></td><td>us-ids.dtd</td></tr><tr><td></td><td>us-ids.xsl</td></tr></table> | | | Documents being submitted | Files | us-ids | 558906100IDS-usidst.xml | | us-ids.dtd | | us-ids.xsl |
| Documents being submitted | Files | | | | | | | | | |
| us-ids | 558906100IDS-usidst.xml | | | | | | | | | |
| | us-ids.dtd | | | | | | | | | |
| | us-ids.xsl | | | | | | | | | |
| Comments | | | | | | | | | | |



ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of
Invention

METHODS AND SYSTEMS FOR INSPECTION OF AN
ENTIRE WAFER SURFACE USING MULTIPLE
DETECTION CHANNELS

Application Number: 10/663603



Confirmation Number: 3534

First Named Applicant: Lionel Kuhlmann

Attorney Docket Number: 5589-06100

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or 6538730 or 6509965 or 6507394 or 6356346
or 6020957 or 5355212 or 6407809 or 6515742
or 6496256 or 6034776 or 5999266 or 5801824
or 5623340 or 5604585 or 5585916 or 4632546
or 20030030050 or 20030030795 or
20020149765 or 20020145732 or
20010028454).pn.

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

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Note: Applicant is not required to submit a paper copy of cited US Published Applications

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Signature

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| Examiner Name | Date |
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